

Application. No. 10/604,323  
Amendment dated December 14, 2005  
Amendment made in response to Notice of Allowance dated September 14, 2005

**Amendments to Claims**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

1. (previously presented) A barrier stack comprising:  
a first sub-barrier layer, the first sub-barrier layer comprises a first sub-barrier conductive barrier material, the first sub-barrier layer includes grain boundaries;  
a second sub-barrier layer disposed above the first sub-barrier layer, the second sub-barrier layer comprises a second sub-barrier conductive barrier material, the second sub-barrier layer includes grain boundaries; and  
passivating elements are provided to passivate grain boundaries on an upper surface of the first sub-barrier layer.
2. (original) The barrier stack of claim 1 serves as a barrier for capacitor over plug structure of a memory cell.
3. (original) The barrier stack of claim 2 wherein the capacitor over plug structure includes a plug having a step over an ILD layer.
4. (previously presented) The barrier stack of claim 1 serves as a barrier for capacitor over plug structure of a plurality of memory cells arranged in a series architecture.
5. (original) The barrier stack of claim 4 wherein the capacitor over plug structure includes a plug having a step over an ILD layer.

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6. (original) The barrier stack of claim 1 serves as a barrier for capacitor over plug structure of a ferroelectric memory cell.
7. (original) The barrier stack of claim 6 wherein the capacitor over plug structure includes a plug having a step over an ILD layer.
8. (previously presented) The barrier stack of claim 1 serves as a barrier for capacitor over plug structure of a plurality of ferroelectric memory cells arranged in a series architecture.
9. (original) The barrier stack of claim 8 wherein the capacitor over plug structure includes a plug having a step over an ILD layer.
10. (cancelled)
11. (cancelled)
12. (cancelled)
13. (cancelled)
14. (cancelled)
15. (cancelled)
16. (cancelled)
17. (cancelled)

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18. (currently amended) The barrier stack of claim 1, 2 or 6 wherein the passivating elements comprises oxygen .

19. (previously presented) The barrier stack of claim 18 wherein:  
the first sub-barrier material comprises Ir, Ru, Rh, Pd, Hf or a combination thereof; and  
the second sub-barrier material comprises Ir, Ru, Rh, Pd, Hf, a conductive oxide or a combination thereof.

20. (previously presented) The barrier stack of claim 19 wherein the grain boundaries of the first and second sub-barrier layers are mismatched.

21. (currently amended) The barrier stack of claim 18 19 wherein the grain boundaries of the first and second sub-barrier layers are mismatched.

22. (cancelled)

23. (currently amended) The barrier stack of claim 1, 2 or 6 wherein:  
the first sub-barrier material comprises Ir, Ru, Rh, Pd, Hf or a combination thereof; and  
the second sub-barrier material comprises Ir, Ru, Rh, Pd, Hf, a conductive oxide or a combination thereof.

24. (previously presented) The barrier stack of claim 23 wherein the grain boundaries of the first and second sub-barrier layers are mismatched.

25. (currently amended) The barrier stack of claim 1, 2 or 6 wherein the grain boundaries of the first and second sub-barrier layers are mismatched.

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26. (currently amended) The barrier stack of claim 1, 2 or 6 23 wherein the passivating elements comprises a size greater than the grain boundaries of the first sub-barrier layer.

27. (previously presented) The barrier stack of claim 26 wherein:  
the first sub-barrier material comprises Ir, Ru, Rh, Pd, Hf or a combination thereof; and  
the second sub-barrier material comprises Ir, Ru, Rh, Pd, Hf, a conductive oxide or a combination thereof.

28. (previously presented) The barrier stack of claim 27 wherein the grain boundaries of the first and second sub-barrier layers are mismatched.

29. (previously presented) The barrier stack of claim 26 wherein the grain boundaries of the first and second sub-barrier layers are mismatched.

30. (currently amended) The barrier stack of claim 1, 2 or 6 further comprises an upper barrier layer disposed above the second sub-barrier layer, the upper barrier layer comprises a conductive oxide.

31 (previously presented) The barrier stack of claim 30 wherein the passivating elements comprises a size greater than the grain boundaries of the first sub-barrier layer.

32. (previously presented) The barrier stack of claim 30 wherein the passivating elements comprises oxygen.

33. (previously presented) The barrier stack of claim 30 wherein:  
the first sub-barrier material comprises Ir, Ru, Rh, Pd, Hf or a combination thereof; and

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the second sub-barrier material comprises Ir, Ru, Rh, Pd, Hf, a conductive oxide or a combination thereof.

34. (previously presented) The barrier stack of claim 30 wherein the grain boundaries of the first and second sub-barrier layers are mismatched.

35. (currently amended) The barrier stack of claim 31 30 wherein the grain boundaries of the upper barrier and second sub-barrier layers are mismatched.

36. (previously presented) A barrier stack comprising:  
a first sub-barrier layer, the first sub-barrier layer comprises a first sub-barrier conductive barrier material, the first sub-barrier layer includes grain boundaries;  
a second sub-barrier layer disposed above the first sub-barrier layer, the second sub-barrier layer comprises a second sub-barrier conductive barrier material, the second sub-barrier layer includes grain boundaries; and  
passivating elements are provided to passivate grain boundaries on an upper surface of the first sub-barrier layer, wherein the passivating elements comprises a size greater than the grain boundaries of the first sub-barrier layer.

37. (previously presented) A barrier stack comprising:  
a first sub-barrier layer, the first sub-barrier layer comprises a first sub-barrier conductive barrier material, the first sub-barrier layer includes grain boundaries;  
a second sub-barrier layer disposed above the first sub-barrier layer, the second sub-barrier layer comprises a second sub-barrier conductive barrier material, the second sub-barrier layer includes grain boundaries;  
wherein grain boundaries of the first and second sub-barrier layers are mismatched; and

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passivating elements are provided to passivate grain boundaries on an upper surface of the first sub-barrier layer.